

# Compact model for the bias-dependent low-frequency noise in organic thin-film transistors due to carrier-number and mobility-fluctuation effects<sup>☆</sup>

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## ABSTRACT

A charge-based compact model for the bias-dependent low-frequency noise in organic thin-film transistors is presented. The model combines the carrier-number fluctuation effect and the fluctuation of the carrier mobility according to the Hooge model to predict the drain-current noise. The model has been verified using experimental data from a large number of organic transistors with two different channel lengths fabricated in the inverted staggered device architecture on a flexible polymeric substrate.

## 1. Introduction

In organic thin-film transistors (TFTs), the semiconductor is a thin, usually polycrystalline layer of conjugated organic molecules [1]. Organic TFTs are typically fabricated at relatively low process temperatures, i.e., below about 100 °C [2], and can thus be utilized as building blocks in flexible electronics applications [3]. The efficient design of electronic systems is accomplished with the help of circuit simulators, which require physics-based compact models that accurately predict the electrical behavior of the transistors. Physics-based compact models need to cover a wide range of transistor properties, such as DC behavior [4,5], AC behavior [6], short-channel effects [7], drain-current variability [8,9] and low-frequency noise (LFN). In organic TFTs, LFN is dominated mainly by carrier-number fluctuations due to grain-boundary traps, and less by carrier scattering at the semiconductor–dielectric interface [10]. Accurate LFN modeling of organic TFTs has been successfully demonstrated by adopting the theory of carrier-number-correlated mobility fluctuations [11,12] and the empirical Hooge approach [13–15].

In this study, a bias-dependent model for the drain-current low-frequency noise (LFN) in organic TFTs is introduced. The charge-based model proposed here takes into account the two discrete effects that constitute the sources of the flicker noise in organic TFTs, namely the noise due to the carrier-number and correlated mobility-fluctuation effect ( $\Delta N$  or McWerther model [16]) and the noise due to the fluctuation

of the charge-carrier mobility ( $\Delta\mu$  or Hooge model [17]). As a result, the model is more flexible in accurately predicting the bias-dependent behavior of LFN in organic TFTs of the inverted staggered device architecture, from the subthreshold regime to the maximum-effective-gate-voltage regime. Additionally, the LFN-model equations are fully combined with a current–voltage compact model for organic TFTs [4, 18], and the complete model is implemented in Verilog-A [19]. For the verification, a large number of organic transistors were fabricated and characterized.

## 2. LFN model derivation

In this section, the derivation of a drain-current LFN model suitable for organic TFTs is presented. As mentioned above, the proposed model treats the flicker noise as the sum of two contributions, namely the noise due to  $\Delta N$  effects and the noise due to  $\Delta\mu$  effects.

For the LFN noise model derived here, the charge-based organic-TFT current–voltage model described in [4] will be used as the basis. The proposed model provides a single current equation that is valid for all operation regions and can be obtained from

$$I_{DS} = \mu W \left( U_T \frac{Q_S - Q_D}{L} + \frac{Q_S^2 - Q_D^2}{2LC'_{ox}} \right), \quad (1)$$

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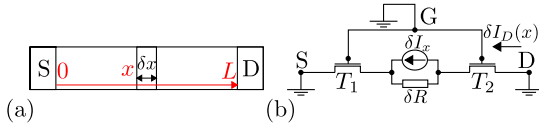


Fig. 1. (a) Schematic of a transistor channel divided into a noisy element located between the positions  $x$  and  $x + \delta x$  and two noiseless pseudo-transistors having channel lengths  $x$  and  $L - x$ , respectively. (b) Small-signal representation [8].

where  $U_T = kT/q$  is the thermodynamic voltage,  $W$  is the channel width,  $L$  is the channel length,  $C'_{ox}$  is the unit-area gate-dielectric capacitance, and  $\mu$  is the effective carrier mobility.  $Q_S$  and  $Q_D$  are the densities of quasi-mobile charges per gate area at the source and drain ends of the channel, respectively, and can be expressed as

$$Q_{S(D)} = aU_T C'_{ox} \mathcal{L} \left\{ \exp \left( \frac{V_{GS(D)} - V_{T0}}{aU_T} \right) \right\}, \quad (2)$$

where  $\mathcal{L}$  is the first branch of the Lambert W function,  $a$  is the sub-threshold slope factor and  $V_{T0}$  is the threshold voltage. The DC model was also extended to cover short-channel and contact resistance effects on the drain-current characteristics [7,20].

## 2.1. $\Delta N$ Model derivation

Here, the impact of local charge-density fluctuations in the carrier channel as one of the sources of the drain-current LFN in organic TFTs will be discussed. This noise originates from local random fluctuations of the carrier density or carrier velocity, leading to a local fluctuation of the drain current [14]. The fluctuation of the drain current around its nominal value is thus considered to be a result of the sum of all local fluctuation contributions along the channel. Following the methodology described in [21] for silicon transistors and in [8] for organic TFTs, the transistor channel is divided into a noisy element located between the positions  $x$  and  $x + \delta x$  and two noiseless pseudo-transistors T1 and T2 that have channel lengths  $x$  and  $L - x$ , respectively (see Fig. 1). The relative local current fluctuation at the position  $x$  of the channel can be described as [8]

$$\frac{\delta I_x}{I_D} = \frac{\delta I_D(x)}{I_D} = \frac{\delta Q_{CH}}{Q_{CH}} + \frac{\delta \beta}{\beta}, \quad (3)$$

where the term  $\delta \beta / \beta$  describes the charge-trapping effects or edge effects [22] on  $\beta = \mu C'_{ox} \frac{W}{L}$ . Attributing all variations exclusively to charge trapping, and by following [23], based on Matthiessen's rule, the carrier mobility, including the effect of the trapping mechanism, can be expressed as

$$\frac{1}{\mu} = \frac{1}{\mu_0} + a_c Q_t \Leftrightarrow \mu = \frac{\mu_0}{1 + a_c Q_t \mu_0}, \quad (4)$$

where  $Q_t = -qN_t$  is the density of trapped charges and  $a_c = \bar{a}_c/q$  is the Coulomb scattering coefficient [21]. Using (4), the following can be obtained:

$$\frac{\delta \beta}{\delta Q_t} = -a_c \mu \beta \quad (5)$$

and the relative current fluctuation can be expressed as

$$\frac{\delta I_D(x)}{I_D} = \left( \frac{1}{Q_{CH}} \frac{\delta Q_{CH}}{\delta Q_t} - a_c \mu \right) \delta Q_t, \quad (6)$$

where  $\delta Q_t$  is the local charge fluctuation related to the fluctuation in the trap density. Furthermore, according to [8], the following can be obtained

$$\frac{\delta Q_{CH}}{\delta Q_t} \approx \frac{Q_{CH}}{Q_{CH} + Q^*/a} = \frac{q_{ch}}{q_{ch} + 1/a}. \quad (7)$$

Similar to some of the widely-used commercial compact models (i.e. BSIM-BULK, EKV) [21,24], charges are normalized according to

$$\frac{Q_{CH}}{q_{ch}} = \frac{Q_D}{q_d} = \frac{Q_S}{q_s} = Q^*, \quad (8)$$

where

$$Q^* = aU_T C'_{ox}. \quad (9)$$

The terms  $q_s$  and  $q_d$  are the normalized charge densities at the source and drain ends of the channel, respectively. By substituting (7) into (6), the relative local current fluctuation can be rewritten as

$$\frac{\delta I_D(x)}{I_D} = \left( \frac{1}{q_{ch} + 1/a} + a^* \mu \right) \frac{\delta Q_t}{Q^*}, \quad (10)$$

where  $a^* = a_c(-Q^*)$  is a parameter related to the Coulomb scattering coefficient given in units of Vs/m<sup>2</sup>. Accordingly, the power spectral density (PSD) of the local noise current source  $\delta I_x$ , normalized to the square of the drain current, is expressed as [21]

$$\frac{S_{\delta I_x^2}}{I_D^2} = \left( \frac{1}{q_{ch} + 1/a} + a^* \mu \right)^2 \frac{S_{\delta Q_t^2}}{(Q^*)^2}. \quad (11)$$

The PSD  $S_{\delta Q_t^2}$  is given by

$$S_{\delta Q_t^2} = \frac{kTq^2 \lambda N_T}{W \delta x f^{AF}}, \quad (12)$$

where  $f$  is the frequency,  $AF$  is the frequency-exponent [25],  $k$  is the Boltzmann constant,  $T$  is the temperature,  $\lambda$  is the tunneling attenuation distance and  $N_T$  is the gate-dielectric volumetric trap density per unit energy (in units of eV<sup>-1</sup> m<sup>-3</sup>).

Following [21], by integrating along the transistor channel, the PSD of the total drain-current fluctuation  $S_{I_D}$ , normalized to the square of the total drain current, can be expressed as

$$\frac{S_{I_D}}{I_D^2} \Big|_{\Delta N} = \frac{1}{L^2} \int_0^L \delta x \frac{S_{\delta I_x^2}}{I_D^2} dx, \quad (13)$$

and by substituting Eqs. (9), (11) and (12) into (13), the following can be obtained:

$$\frac{S_{I_D}}{I_D^2} \Big|_{\Delta N} = \frac{q^4 \lambda N_T}{W L^2 a^2 k T C_{ox}^2 f^{AF}} \int_0^L \left( \frac{1}{q_{ch} + 1/a} + a^* \mu \right)^2 dx. \quad (14)$$

Solving the integral above yields:

$$\frac{S_{I_D}}{I_D^2} \Big|_{\Delta N} = C_{noise}^* |_{\Delta N} \times B_{noise}^* (q_{ch}) |_{\Delta N} \quad (15)$$

where

$$C_{noise}^* |_{\Delta N} = \frac{q^4 \lambda N_T}{W L a^2 k T C_{ox}^2 f^{AF}} \quad (16)$$

and

$$B_{noise}^* (q_s, q_d) |_{\Delta N} = \frac{1}{i_d} (B_1 + B_2 + B_3 + B_4). \quad (17)$$

The coefficients  $B_1$ ,  $B_2$ ,  $B_3$  and  $B_4$  are given by

$$\begin{aligned} B_1 &= \left( \frac{2(a-1)a^* \mu}{a} + 1 \right) \ln \left( \frac{1 + a q_s}{1 + a q_d} \right), \\ B_2 &= \left( \frac{1-a}{1+a q_s} - \frac{1-a}{1+a q_d} \right), \\ B_3 &= i_d (a^* \mu)^2, \\ B_4 &= 2 (a^* \mu) (q_s - q_d). \end{aligned} \quad (18)$$

The normalized drain current  $i_d$  can be expressed as  $i_d = I_D / \mu (aU_T)^2 C'_{ox} W / L$ . Similarly as demonstrated previously for silicon transistors [26,27], the results we obtained for the  $1/f$  noise in organic TFTs are closely related to those derived in [8] for the drain-current variability, since the physical mechanisms at the origin of both phenomena are similar.

## 2.2. $\Delta \mu$ Model derivation

The drain-current flicker noise arising from the fluctuations of the carrier mobility can be modeled using the so-called Hooge ( $\Delta \mu$ ) model.

Accordingly, the total PSD of a local noise-current source  $\delta I_x$  due to the delta  $\mu$  effect can be expressed as [21]

$$\frac{S_{\delta I_x}}{I_D^2} \Big|_{\Delta\mu} = \frac{a_H q}{W \delta x (-Q_{ch}) f^{AF}}, \quad (19)$$

where  $a_H$  is the unitless Hooge parameter. By using Eq. (13) and integrating along the channel, the PSD of the total fluctuation of the drain current due to the  $\Delta\mu$  effect, normalized to the square of the total drain current, is then given by

$$\frac{S_{I_D}}{I_D^2} \Big|_{\Delta\mu} = C_{noise}^* \Big|_{\Delta\mu} \times B_{noise}^* (q_{ch}) \Big|_{\Delta\mu}, \quad (20)$$

where

$$C_{noise}^* \Big|_{\Delta\mu} = \frac{a_H q^2}{W L k T a C'_{ox} f^{AF}} \quad (21)$$

and

$$B_{noise}^* \Big|_{\Delta\mu} = \frac{1}{i_d} (\ln q_s - \ln q_d + q_s - q_d) \quad (22)$$

is the bias-dependent factor.

### 2.3. Total drain-current low-frequency noise

The total LFN as the sum of the two noise sources described above can be expressed as follows:

$$\frac{S_{I_D}}{I_D^2} = \frac{S_{I_D}}{I_D^2} \Big|_{\Delta N} + \frac{S_{I_D}}{I_D^2} \Big|_{\Delta\mu} \quad (23)$$

### 3. Devices and measurements

In order to verify the model, organic p-channel TFTs with a channel width ( $W$ ) of  $100 \mu\text{m}$  and channel lengths ( $L$ ) of  $40 \mu\text{m}$  and  $20 \mu\text{m}$  were fabricated on a  $125 \mu\text{m}$ -thick flexible polyethylene naphthalate (PEN) substrate in the inverted staggered (bottom-gate, top-contact) device architecture using polyimide shadow masks [28]. The TFTs consist of  $30 \text{ nm}$ -thick aluminum gate electrodes, an  $8 \text{ nm}$ -thick hybrid  $\text{AlO}_x/\text{SAM}$  gate dielectric, a  $25 \text{ nm}$ -thick vacuum-deposited layer of the small-molecule organic semiconductor DNTT, and  $30 \text{ nm}$ -thick gold (Au) source and drain contacts [28]. The maximum process temperature was  $60^\circ\text{C}$ .

**Protocol for the current–voltage measurements:** All transfer characteristics were measured at a drain–source voltage ( $V_{DS}$ ) of  $-3.0 \text{ V}$  by sweeping the gate–source voltage ( $V_{GS}$ ) from  $0$  to  $-3.0 \text{ V}$  with a step size of  $-50 \text{ mV}$ . All measurements were performed in ambient air at room temperature.

**Protocol for the LFN measurements:** All LFN measurements were performed with the TFTs biased in saturation ( $V_{DS} = -3.0 \text{ V}$ ) and with gate–source voltages ( $V_{GS}$ ) of  $-1.2 \text{ V}$ ,  $-1.5 \text{ V}$ ,  $-2.0 \text{ V}$ ,  $-2.5 \text{ V}$  and  $-3.0 \text{ V}$ . For each applied gate–source voltage, the PSD of the drain-current noise was measured in the frequency range between  $1 \text{ Hz}$  and  $10^5 \text{ Hz}$ . All measurements were performed in ambient air at room temperature. Note that small signal measurements were not performed. In the sub-threshold regime, a cutoff frequency of approximately  $800 \text{ Hz}$  and  $10 \text{ Hz}$  was calculated [29], at the gate–source voltages of  $-1.5 \text{ V}$  and  $-1.2 \text{ V}$ , respectively.

Approximately 15 TFTs of each channel length ( $20 \mu\text{m}$  and  $40 \mu\text{m}$ ) were measured. The mean-value characteristics were generated from the measured transfer characteristics by calculating the sample-mean  $E[I_{DS}]$  of the measured drain current  $I_{DS}$  at each applied gate–source voltage. The mean-value transconductance  $E[G_m] = \Delta E[I_{DS}] / \Delta V_{GS}$  was approximated from the mean-value transfer characteristics. Each PSD sample of the drain-current noise  $S_{I_D}$  was multiplied by the corresponding frequency, the average  $S_{I_D} f$  value was calculated in the frequency range between  $10 \text{ Hz}$  and  $100 \text{ Hz}$ , and the mean value of the noise  $E[S_{I_D} f]$  was calculated by averaging over all TFTs. This

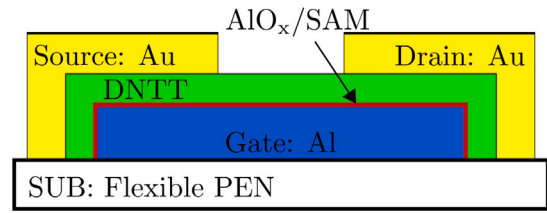


Fig. 2. Schematic cross-section of the organic TFTs fabricated in the inverted staggered (bottom-gate, top-contact) device architecture [9].

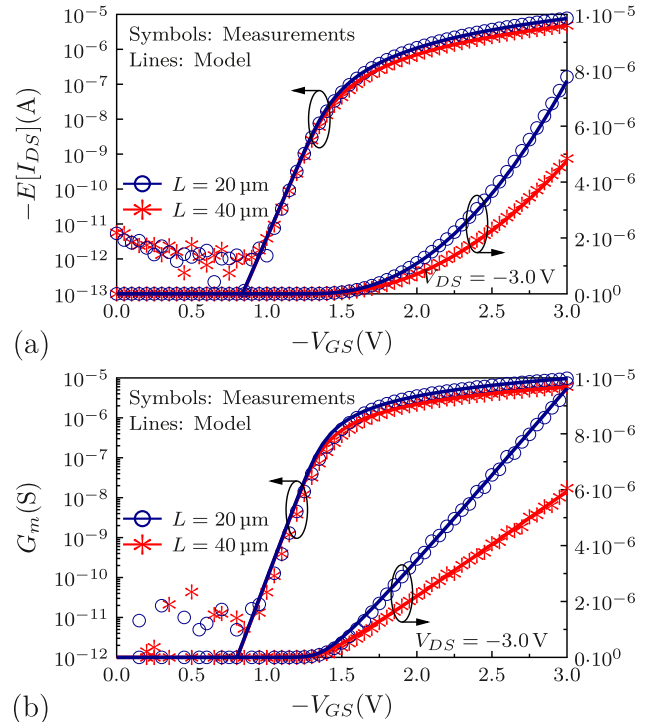
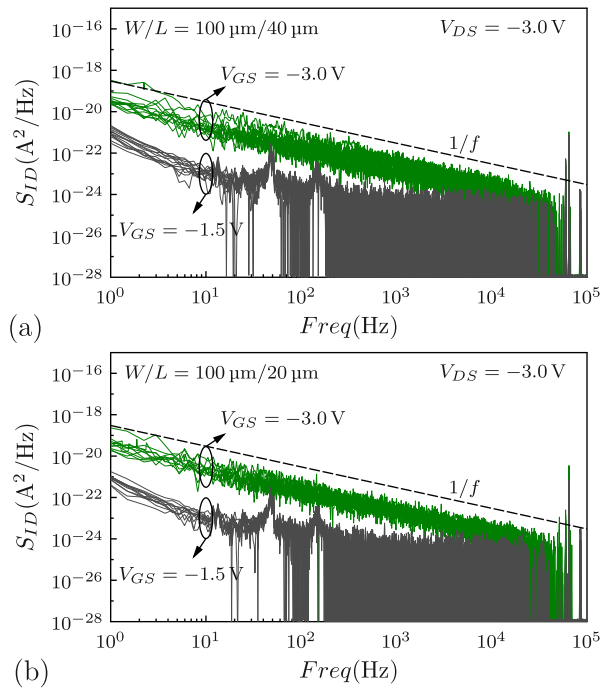


Fig. 3. (a) Mean-value drain current  $E[I_{DS}]$  and (b) transconductance  $g_m$  plotted versus the gate–source voltage  $V_{GS}$  of TFTs with channel lengths of  $40 \mu\text{m}$  and  $20 \mu\text{m}$ . The transfer characteristics were recorded in the saturation regime ( $V_{DS} = -3.0 \text{ V}$ ). Symbols: Values calculated from experimental data. Lines: Simulation results.

procedure was executed for each gate–source voltage at which a noise measurement had been performed. For gate–source voltages in the deep subthreshold regime, the corner frequency value of the noise spectrum is relatively small and thus the white-noise regime is noticeable from lower frequency values [30]. Additionally, in the same biasing regime, the deviation of the noise spectrum from the ideal  $1/f$  LFN trend is quite large, leading to  $AF$  exponent values smaller than unity [25]. This was taken into account during the calculation of the experimental  $S_{I_D} f$  values (see Fig. 2).

### 4. Results and discussion

Fig. 3 shows the mean-value transfer characteristics and the transconductance  $G_m$  of TFTs with channel lengths of  $40 \mu\text{m}$  and  $20 \mu\text{m}$ , recorded using the current–voltage-measurement protocol described above. Experimental data and simulation results are shown as symbols and lines, respectively, and both are in good agreement, except for the off-state region (i.e., the range of gate–source voltages between  $0$  and  $-0.9 \text{ V}$ ), which is not covered by the model. For the fabricated TFTs, as previously described in [31], hopping mainly limits the transport. However, in the current work, in order to arrive finally at closed form expressions for the noise figure, a constant effective mobility has



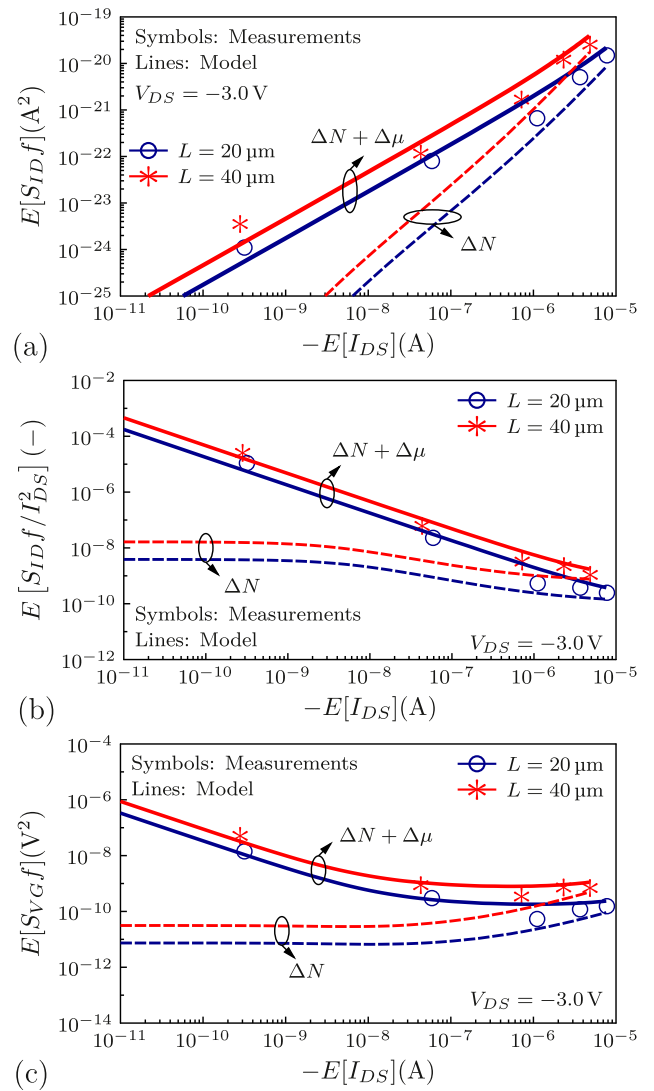
**Fig. 4.** Flicker-noise spectra of TFTs with channel lengths  $L$  of (a)  $40\ \mu\text{m}$  and (b)  $20\ \mu\text{m}$ , measured at gate-source voltages ( $V_{GS}$ ) of  $-1.5\ \text{V}$  and  $-3.0\ \text{V}$  and with a drain-source voltage  $V_{DS}$  of  $-3.0\ \text{V}$ , i.e., with the TFTs operating in saturation. The dashed line indicates the ideal  $1/f$  slope.

been considered, which gives a good approximation according to the transfer characteristics shown in Fig. 3. In Fig. 4, the discrete noise spectra of the TFTs, measured at gate-source voltages ( $V_{GS}$ ) of  $-1.5\ \text{V}$  (subthreshold regime) and  $-3.0\ \text{V}$  (maximum gate-source voltage), are depicted. In all cases, the measured flicker noise represents typical  $1/f^{AF}$  behavior, particularly at lower frequencies between  $1\ \text{Hz}$  and  $100\ \text{Hz}$ , a fact which is in agreement with findings presented in [14]. The peaks appeared in the  $V_{GS} = -1.5\ \text{V}$  spectra, occur due to the AC power line.

In Fig. 5(a) and (b), the PSDs of the average LFN  $S_{ID}$  and  $S_{ID}/I_{DS}^2$  at a frequency of  $1\ \text{Hz}$  of TFTs with channel lengths of  $40\ \mu\text{m}$  and  $20\ \mu\text{m}$  are plotted versus the drain current  $I_{DS}$ . Both the  $S_{ID}f$  and the  $S_{ID}f/I_{DS}^2$  PSDs follow a trend that is also typically observed in silicon transistors, namely that the noise is smaller in TFTs that have a smaller active area (product of channel length and channel width) [25]. The  $\Delta\mu$  model-component covers the noise behavior at lower drain currents, predicting accurately the observed increase of the noise with decreasing drain current in the subthreshold regime (i.e., for drain currents below about  $10^{-7}\ \text{A}$ ), where the  $\Delta\mu$  effect is more prominent, similar to silicon transistors [21]. The  $\Delta N$  model-component is used to predict the measured LFN towards higher drain current. In the subthreshold regime, the distance between localized states is relatively large, which is expected to affect the mobility fluctuation [31], whereas in the above-threshold regime, the hopping distance will be smaller, and thus the effect of the Hooe parameter  $a_H$  is expected to be minimal. Overall, the agreement between model ( $\Delta N + \Delta\mu$  sum) and experiment is quantitatively satisfactory, both in the below-threshold and the above-threshold regimes of operation.

The noise PSD referred to the gate,  $S_{VG} = S_{ID}/G_m^2$ , is depicted in Fig. 5(c). As can be seen, the LFN is smaller in the TFTs that have a smaller active area, i.e., a smaller channel length. Again, the model correctly predicts the experimentally measured LFN in both the subthreshold- and the above-threshold regimes.

Table 1 summarizes the values of the parameters  $N_T$ ,  $a^*$  and  $a_H$  extracted from the LFN model for each channel length in saturation



**Fig. 5.** Power spectral densities (a)  $S_{ID}$  and (b)  $S_{ID}/I_{DS}^2$  at a frequency of  $1\ \text{Hz}$ , measured at a drain-source voltage  $V_{DS}$  of  $-3.0\ \text{V}$  and plotted versus the drain current  $I_{DS}$ . (c) Input-referred noise  $S_{VG}f$  of the same transistors. All measurements were performed with the TFTs biased in saturation ( $V_{DS} = -3.0\ \text{V}$ ). Symbols: Values calculated from experimental data. Lines: Simulation results.

**Table 1**  
Extracted parameters of the LFN model.

	$N_T$ ( $\text{eV}^{-1}\text{cm}^{-3}$ )	$a^*$ ( $\text{Vs/m}^2$ )	$a_H$ (-)
$L = 40\ \mu\text{m}$	$1.3 \times 10^{11}$	1465	$8.2 \times 10^{-2}$
$L = 20\ \mu\text{m}$	$1.3 \times 10^{10}$	1375	$7.8 \times 10^{-3}$

( $V_{DS} = -3.0\ \text{V}$ ). The trap densities  $N_T$  predicted by the model are similar to the values reported previously for organic TFTs [12]. Following a similar approach as in [8], a different set of the model parameters ( $N_T$ ,  $a^*$  and  $a_H$ ) was extracted for the two different available device geometries. The value of  $N_T$  was found to be smaller in the TFTs that have a smaller active area. This finding is consistent with results presented in [8]. The extracted value of the Hooe parameter  $a_H$  has also been found to be consistent with the values reported in [32] for several organic-TFT technologies.

## 5. Conclusions

In conclusion, we have developed a semi-physical bias-dependent charge-based low-frequency noise model for organic thin-film transistors. The proposed model is based on charge carrier-number fluctuation-correlated mobility fluctuation ( $\Delta N$ ) and mobility-fluctuation (Hooge) ( $\Delta\mu$ ) effects, and it can be applied to TFTs fabricated in the inverted staggered device architecture. We have shown that the drain-current noise is smaller in TFTs with a smaller active area. The  $\Delta N$  effect was found to dominate over the  $\Delta\mu$  effect in the above-threshold regime. The observed trend of the drain-current-normalized noise increasing with decreasing drain current in the subthreshold regime can be attributed mainly to the  $\Delta\mu$  effect. Regardless of the channel length, the results of the proposed model are in good agreement with the experimentally measured bias-dependent drain-current LFN of organic TFTs, especially in the below and above-threshold regimes.

## Declaration of competing interest

The authors declare that they have no known competing financial interests or personal relationships that could have appeared to influence the work reported in this paper.

## Data availability

Data will be made available on request.

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